



NOV 18 2005

<b>Filing No. 1449 (Modified)</b>	Atty Docket No. NOVLP037C1/ NVLS- 000519C1	Application No.: 10/773,821
<b>Information Disclosure Statement By Applicant</b>	Applicant: van Schravendijk et al.	Filing Date February 5, 2004

## **U.S. Patent Documents**

### **Foreign Patent or Published Foreign Patent Application**

## **Other Documents**

Other Documents		
Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Li et al., "Methods of Forming Moisture Barrier for Low K Film Intergration with Anti-Reflective Layers", Novellus Systems, Inc., Appln. No. 11/168,013, filed June 27, 2005, pages 1-25. [NOVLP128/NVLS-3043]
	C2	U.S. Office Action mailed October 24, 2002, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]
	C3	U.S. Office Action mailed May 21, 2003, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]

**Examiner:** Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.